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(54) Title: VACUUM APPARATUS TEMPERATURE SENSOR ASSEMBLY

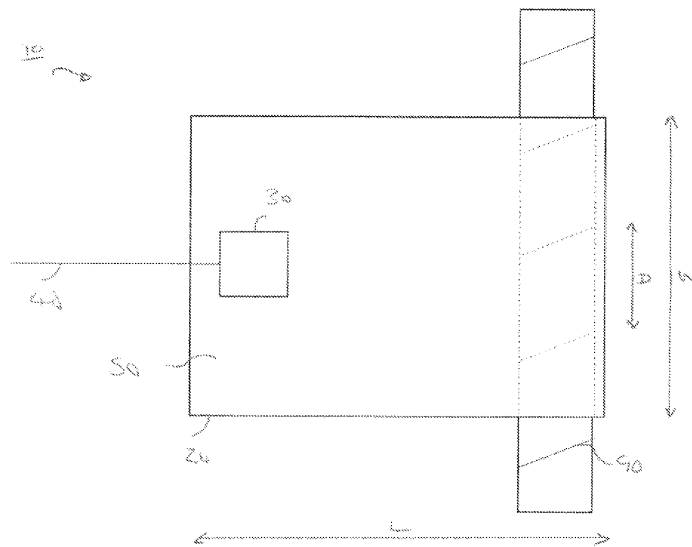


Figure 1A

(57) Abstract: A vacuum apparatus temperature sensor assembly for measuring the temperature of a vacuum apparatus and a method are disclosed. The vacuum apparatus temperature sensor assembly comprises: a sheet substrate configured to conform to a shape of an item, equipment or apparatus whose temperature is to be determined; and a temperature sensor thermally coupled with the sheet substrate, wherein the sheet substrate is configured to provide a thermal path from the apparatus to the temperature sensor. In this way, the substrate provides a larger area than that of the temperature sensor to couple with the apparatus which enables the average temperature of the apparatus to be more reliably and accurately conveyed to the temperature sensor and make the temperature measurements less reliant on the exact placing of the temperature sensor with respect to the apparatus.

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